

(12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(19) World Intellectual Property
Organization
International Bureau

(43) International Publication Date
02 January 2020 (02.01.2020)



(10) International Publication Number
WO 2020/005611 A1

(51) International Patent Classification:
H01L 21/673 (2006.01)

(21) International Application Number:
PCT/US2019/037454

(22) International Filing Date:
17 June 2019 (17.06.2019)

(25) Filing Language: English

(26) Publication Language: English

(30) Priority Data:
20 2018 103 663.7 27 June 2018 (27.06.2018) DE
16/185,546 09 November 2018 (09.11.2018) US
20 2019 101 793.7 29 March 2019 (29.03.2019) DE

(71) Applicant: **MURATA MACHINERY, LTD.** [JP/JP]; 3
Minami Ochiai-cho, Kisshoin, Minami-ku, Kyoto-shi, Ky-
oto, 601-8326 (JP).

(71) Applicant (for AG only): **MURATA MACHINERY USA,
INC.** [US/US]; 2120 Queen City Drive, Charlotte, North
Carolina 28208 (US).

(72) Inventors: **SCHOBBER, Thomas**; c/o Murata Machinery,
Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi,
Kyoto, 612-8686 (JP). **RAHRBACH, Bernd**; c/o Murata
Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku,
Kyoto-shi, Kyoto, 612-8686 (JP). **WOHANKA, Christ-
ian**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishi-
ro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP).
FENNER, Yves; c/o Murata Machinery, Ltd., 136, Takeda
Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686
(JP). **DOVIDS, Gerhard**; c/o Murata Machinery, Ltd.,
136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Ky-
oto, 612-8686 (JP). **FIDDES, John**; c/o Murata Machinery,
Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi,
Kyoto, 612-8686 (JP).

(74) Agent: **MEDLEY, Peter**; 1800 Alexander Bell Drive,
Suite 200, Reston, Virginia 20191-5465 (US).

(54) Title: SUBSTRATE CARRIER AND SUBSTRATE CARRIER STACK

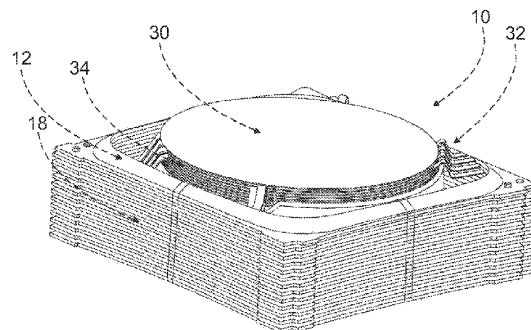


Fig. 2

(57) Abstract: A substrate carrier stack includes substrate carriers of only one type which are stacked or stackable on each other and carry a respective plate-shaped substrates within an inner accommodation space of the substrate carrier stack. The substrate carriers each include positioning formations. Positioning formations of each pair of an upper substrate carrier and a lower substrate carrier are mutually engaged or engageable, if the upper substrate carrier and the lower substrate carrier are properly positioned relative to each other.

[Continued on next page]



WO 2020/005611 A1

(81) Designated States (*unless otherwise indicated, for every kind of national protection available*): AE, AG, AL, AM, AO, AT, AU, AZ, BA, BB, BG, BH, BN, BR, BW, BY, BZ, CA, CH, CL, CN, CO, CR, CU, CZ, DE, DJ, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IR, IS, JO, JP, KE, KG, KH, KN, KP, KR, KW, KZ, LA, LC, LK, LR, LS, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PA, PE, PG, PH, PL, PT, QA, RO, RS, RU, RW, SA, SC, SD, SE, SG, SK, SL, SM, ST, SV, SY, TH, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW.

(84) Designated States (*unless otherwise indicated, for every kind of regional protection available*): ARIPO (BW, GH, GM, KE, LR, LS, MW, MZ, NA, RW, SD, SL, ST, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, RU, TJ, TM), European (AL, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HR, HU, IE, IS, IT, LT, LU, LV, MC, MK, MT, NL, NO, PL, PT, RO, RS, SE, SI, SK, SM, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, KM, ML, MR, NE, SN, TD, TG).

Published:

— with international search report (Art. 21(3))